



# Patent [19]

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## [54] PROCESS AND DEVICE FOR CLEANING GAS IN CLEAN ROOM

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## [57] ABSTRACT

**PROBLEM TO BE SOLVED:** To provide a gas cleaning process and a device for creating a superclean space in a clean room from which a gaseous toxic component is removed together with fine particles.

**SOLUTION:** A device for cleaning a cleaning room 5 or gas in a local space in the clean room 5 is provided with a dust removing filter 4 for removing the fine particles and the gaseous toxic component in gas, an adsorption device 9 filled with an adsorption material and a photocatalyst device D constituted of a photocatalyst 10 and a light source 11 emitting beam to the catalyst 10, and it is recommendable that adsorption material is active carbon and/or ion exchange fibers, that the photocatalyst is TiO<sub>2</sub> and that a germicidal lamp generating ultraviolet beam of 254 nm for the light source emitting the beam.

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